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PATENT
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IN THE U.S. PATENT AND TRADEMARK OFFICE
TC 2800 MAIL ROOM

Applicant: Victor KATSAP et al. Conf. No.: UNKNOWN
Appl. No.: 09/414,004 Group: 2881
Filed: October 7, 1999 Examiner: K. Fernandez
For: LENS ARRAY FOR ELECTRON BEAM LITHOGRAPHY TOOL

PROPOSED AMENDMENT AFTER FINAL

Assistant Commissioner for Patents
Washington, D.C. 20231

DUE: January 1, 2002

Sir:

In response to the Office Action mailed on October 10, 2001, the following amendments and remarks are respectfully submitted in connection with the above-identified application.

IN THE SPECIFICATION

Please amend the paragraph starting on line 20 of page 3 as follows:

Figures 6(a), 6(b), and 6(c) illustrate the potential across alternative mesh grids. Figure 6(c) specifically illustrates a mesh grid arrangement where the outward two meshes have a curved shape.

Please amend the paragraph starting on line 10 of page 8 with as follows: